

IN THE CLAIMS:

Please cancel non-elected claims 7-13 without prejudice or disclaimer.

Please amend the claims as follows:

1.(Currently Amended) A manufacturing apparatus comprising:

a loading chamber;

a transporting chamber coupled to the loading chamber;

a plurality of film formation chambers coupled to the transporting chamber;

a processing chamber coupled to the transporting chamber;

wherein each of the plurality of film formation chambers is coupled to a vacuum evacuation processing chamber for making the inside of the film formation chamber vacuum;

wherein each of the plurality of film formation chambers comprises:

an alignment means for performing a position alignment of a mask and a substrate;

a substrate holding means;

an evaporation source holder; and

a means for moving the evaporation source holder;

wherein the evaporation source holder comprises:

a container that seals an evaporation material;

a means for heating the container; and

a shutter ~~formed~~ provided over the container;

wherein the processing chamber is coupled to a vacuum evacuation processing chamber for providing a vacuum state,

wherein a plurality of plate heaters are disposed within the processing chamber so as to overlap with each other and [[open]] have gaps therebetween, and

wherein the processing chamber can perform a vacuum heating on a plurality of substrates.

2.(Currently Amended) A manufacturing apparatus according to claim 1, wherein ~~[[a]]~~ the means for moving the evaporation source holder functions to move the evaporation source holder in an x-axis direction at a certain pitch, and functions to move the evaporation source holder in a y-axis direction at a certain pitch.

3.(Currently Amended) A manufacturing apparatus according to claim ~~[[1]]~~ 2, wherein the evaporation source holder is rotated when switching between the x-axis direction and the y-axis direction.

4.(Original) A manufacturing apparatus according to claim 1, wherein a hole of an opening surface area S2, which is smaller than an opening surface area S1 of the container, is opened in the shutter.

5.(Currently Amended) A manufacturing apparatus according to claim 1, wherein a film thickness monitor is ~~formed~~ provided adjacent to the evaporation source holder.

6-13.(Canceled)

14.(New) A manufacturing apparatus comprising:
a transporting chamber;
a film formation chamber coupled to the transporting chamber, wherein the film formation chamber comprises an evaporation source holder for forming an electroluminescence layer over a substrate; and
a processing chamber coupled to the transporting chamber, wherein the processing chamber is capable of performing a vacuum heating on a plurality of substrates simultaneously.

15.(New) A manufacturing apparatus according to claim 14, wherein the evaporation source holder comprises a heater.

16.(New) A manufacturing apparatus according to claim 14, wherein the evaporation source holder comprises a shutter having a hole.

17.(New) A manufacturing apparatus according to claim 14, wherein a film thickness monitor is provided adjacent to the evaporation source holder.

18.(New) A manufacturing apparatus according to claim 14, wherein the electroluminescence layer comprises at least one selected from the group consisting of a hole injecting layer, a hole transporting layer, a light emitting layer, an electron transporting layer, and an electron injecting layer.

19.(New) A manufacturing apparatus comprising:
a transporting chamber;
a film formation chamber coupled to the transporting chamber, wherein the film formation chamber comprises an evaporation source holder for forming an electroluminescence layer over a substrate; and
a processing chamber coupled to the transporting chamber, wherein the processing chamber comprises a plurality of plate heaters, and is capable of performing a vacuum heating on a plurality of substrates simultaneously.

20.(New) A manufacturing apparatus according to claim 19, wherein the evaporation source holder comprises a heater.

21.(New) A manufacturing apparatus according to claim 19, wherein the evaporation source holder comprises a shutter having a hole.

22.(New) A manufacturing apparatus according to claim 19, wherein a film thickness monitor is provided adjacent to the evaporation source holder.

23.(New) A manufacturing apparatus according to claim 19, wherein the electroluminescence layer comprises at least one selected from the group consisting of a hole injecting layer, a hole transporting layer, a light emitting layer, an electron transporting layer, and an electron injecting layer.

24.(New) A manufacturing apparatus comprising:
a transporting chamber;
a film formation chamber coupled to the transporting chamber, wherein the film formation chamber comprises an evaporation source holder for forming an electroluminescence layer over a substrate, and a means for moving the evaporation source holder; and
a processing chamber coupled to the transporting chamber, wherein the processing chamber is capable of performing a vacuum heating on a plurality of substrates simultaneously.

25.(New) A manufacturing apparatus according to claim 24, wherein the means for moving the evaporation source holder functions to move the evaporation source holder in an x-axis direction at a certain pitch, and functions to move the evaporation source holder in a y-axis direction at a certain pitch.

26.(New) A manufacturing apparatus according to claim 25, wherein the evaporation source holder is rotated when switching between the x-axis direction and the y-axis direction.

27.(New) A manufacturing apparatus according to claim 24, wherein the evaporation source holder comprises a heater.

28.(New) A manufacturing apparatus according to claim 24, wherein the evaporation source holder comprises a shutter having a hole.

29.(New) A manufacturing apparatus according to claim 24, wherein a film thickness monitor is provided adjacent to the evaporation source holder.

30.(New) A manufacturing apparatus according to claim 24, wherein the electroluminescence layer comprises at least one selected from the group consisting of a hole injecting layer, a hole transporting layer, a light emitting layer, an electron transporting layer, and an electron injecting layer.

31.(New) A manufacturing apparatus comprising:

a transporting chamber;

a film formation chamber coupled to the transporting chamber, wherein the film formation chamber comprises an evaporation source holder for forming an electroluminescence layer over a substrate, and a means for moving the evaporation source holder; and

a processing chamber coupled to the transporting chamber, wherein the processing chamber comprises a plurality of plate heaters, and is capable of performing a vacuum heating on a plurality of substrates simultaneously.

32.(New) A manufacturing apparatus according to claim 31, wherein the means for moving the evaporation source holder functions to move the evaporation source holder in an x-axis direction at a certain pitch, and functions to move the evaporation source holder in a y-axis direction at a certain pitch.

33.(New) A manufacturing apparatus according to claim 32, wherein the evaporation source holder is rotated when switching between the x-axis direction and the y-axis direction.

34.(New) A manufacturing apparatus according to claim 31, wherein the evaporation source holder comprises a heater.

35.(New) A manufacturing apparatus according to claim 31, wherein the evaporation source holder comprises a shutter having a hole.

36.(New) A manufacturing apparatus according to claim 31, wherein a film thickness monitor is provided adjacent to the evaporation source holder.

37.(New) A manufacturing apparatus according to claim 31, wherein the electroluminescence layer comprises at least one selected from the group consisting of a hole injecting layer, a hole transporting layer, a light emitting layer, an electron transporting layer, and an electron injecting layer.